

VertaCure[™] **PLP**

Automated Panel-based Vacuum Curing System



The VertaCure™ PLP is an automated panel-based vacuum cure system for polyimide/PBO cure, D2P bonding, low-temperature cure and pre-metal degas. The VertaCure PLP brings the YES industry-leading vacuum cure technology to panels from 400 mm to 550 mm, and leverages the VertaCure family's proven vertical laminar flow for excellent particle performance. The VertaCure PLP's two process modules hold 12 panels each, with automated loading and unloading via EFEM. Active heating and cooling provide rapid ramp-up and ramp-down. For the precise control and uniformity that innovative panel-based applications require, the VertaCure PLP delivers superior process results.

The Vacuum Cure Advantage

- 3.5 hours vs. 8+ hours for atmospheric
- Laminar flow reduces/eliminates particles
- More complete cure (5x less outgassing)
- Less film stress and low panel warpage

COMMON APPLICATIONS

Polyimide/PBO cure
Hybrid and D2P bonding
Pre-metal degas
Low temp polymer cure

Yield Engineering Systems, Inc.

Call: 1-510-954-6889 (worldwide) or 1-888-YES-3637 (US toll free) www.yieldengineering.com



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SPECIFICATIONS

DESCRIPTION		SPECIFICATION	
Environment Cleanliness		Class 1 (ISO 3)	
EFEM Cleanliness		Class 1 (ISO 3)	
Max Temp		350°C	
WiW Temp Uniformity		± 2% during dwell after stabilization (based on panel type)	
WtW Temp Uniformity		± 1% at dwell after stabilization (based on panel type)	
Glass/CCL	Ramp-rate	Maximum 8.0°C/min from 100°C to 300°C (slope)	
	Ramp-down	Maximum 3.0°C/min from 300°C to 100°C (slope)	
Up-time		≥ 90%	
MTTR		≤ 8 hours	
Warpage		≤ 3 mm one side	
Process Pressure		Sub-atmospheric	
Process Recipe		YES BKM recipe: one-step process Customer-specified recipe: multi-step process	
Panel Size		510 mm X 515 mm, 410 mm X 515 mm, and smaller	
Load Port Quantity		2	
Process Gas Type		N₂ gas (preheated) - Process grade N₂ preferred	
MFC		N₂ calibrated MFC (max 1000 SLM)	
Pump		Option to be provided by customer (Busch COBRA DS 0080 or equivalent)	
Standard Cooling		Forced air cooling outside of chamber	
Pump Exhaust		Scrubber-max flow 94 CFM (provided by customer)	
Aligner		Purchasable option	
Safety Compliance		SEMI S2 and S8, CE and NFPA79 compliance	
Chamber Material		Stainless steel chamber 316L	
Process Capability		One process module for 12 panels, Two process modules for 24 panels	
O2 Concentration		<20 ppm after multiple pump and purge	
Warranty		12 months after acceptance	
SEMI Equipment Communication Standar		ard 2 Message Content (SECS II)	SEMI E5
Generic Model for Communications and Co		Control of SEMI Equipment (GEM) ¹	SEMI E30
High-Speed SECS Message Services Generi		eric Services (HSMS)	SEMI E37
High-Speed SECS Message Services Single		e-Session Mode (HSMS-SS)	SEMI E37.1
Standard for Carrier Management (CMS)			SEMI E87
Specification for Substrate Tracking (STS)			SEMI E90
Specification for Process Job Management		nt (PJM)	SEMI E40
Specification for Control Job Management		nt (CJM)	SEMI E94
Operating System			Windows-based

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